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Sheet

1

of

2

Application Number

Not Yet Received 10596373

Filing Date

December 10, 2004

**First Named Inventor**

Aviram Tam

### Art Unit

Not Yet Received	4174
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Examiner Name

Kenny Cese
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Attorney Docket Number

40006317-0097-002

## U. S. PATENT DOCUMENTS

Examiner Signature	/Kenny Cese/	Date Considered	04/16/2011
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PTO/SB/08B (07-05)

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		Application Number	10596373
		Filing Date	December 10, 2004
		First Named Inventor	Aviram Tam
		Art Unit	<del>Not Yet Assigned</del> 4174
		Examiner Name	<del>Not Yet Assigned</del> Kenny Cese
Sheet 2	of 2	Attorney Docket Number	40006317-0097-002

NON PATENT LITERATURE DOCUMENTS			
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/K.C./		APPLIED MATERIALS ISRAEL, LTD, International Search Report and Written Opinion, PCT/US2004/041884, 27 April 2005, pp	
/K.C./		LEE TAE YONG ET AL.: "Experimental methodology of contact edge roughness on sub-100 nm pattern", Proceedings of SPIE: 24 May 2004, 10 pp	
/K.C./		BUNDAY BENJAMIN D ET AL.: "CD-SEM Measurement of Line Edge Roughness Test Patterns for 193 nm Lithography", Proceedings of SPIE: July 2003, 15 pp	

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